



1762/4

216-028A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : KATSIR, D. ET AL.
Serial No. : 09/745,347
Filed : December 21, 2000
For : METHOD FOR PRODUCING HIGH SURFACE
AREA FOIL ELECTRODES
Art Unit : 1762
Examiner : Brian Talbot

11/3/03
H. J. D.
1/1/03

New York, NY 10036
January 23, 2003

Commissioner for Patents
Washington, D.C. 20231

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AMENDMENT

This Amendment is being filed in response to the Office Action that was mailed July 23, 2002. Kindly amend the subject application as follows:

IN THE CLAIMS

Kindly amend claim 1 as follows:

1. (amended) A method for increasing the surface area of a substrate, comprising the steps of:
- (a) placing the substrate in an inert atmosphere, having a pressure of between 10^{-3} torr and 10^{-2} torr, into which oxygen has been introduced at a pressure of from one to two orders of magnitude less than said pressure of said inert atmosphere; and
 - (b) evaporating a valve metal onto the substrate under said oxygen-containing inert atmosphere, whereby the product has a fractal-like surface structure.

131

Kindly cancel claims 4 and 5.